

**Listing of Claims:**

Claim 1. (canceled)

Claims 2 through 10. (canceled)

Claim 11. (currently amended)      A lens, comprising:  
a concave-shaped substrate consisting essentially of a plastic material which is temperature-stable up to at least 100° C.; and  
a reflecting surface on said substrate constructed as a cold-light mirror consisting essentially of a plurality of layers of different refraction coefficients applied to said substrate by means of one of: a plasma impulse (Pi) process, a chemical vaporization process (CVD) and a ~~phase~~plasma-impulse chemical vaporization process (PICVD).

Claim 12. (previously presented)      The lens of claim 11 wherein said plurality of layers is applied by means of a chemical plasma-impulse vaporization process (PICVD).

Claim 13. (previously presented)      The lens of claim 12 wherein the total duration of the plasma action amounts to at least 1/1000 of the total action-free time span, and is at most equal to this time span.

Claim 14. (previously presented)      The lens of claim 12 wherein the coating rate of the plasma action lasts between 0.1 and 10 ms.

Claim 15. (previously presented)      The lens of claim 13 wherein the coating rate of the plasma action per time unit and per surface unit is > 10 nanometers/min.

Claim 16. (previously presented)      The lens of claim 12 wherein said substrate is a material selected from the group consisting of:

Cycloolefin polyers (COP)  
Cycloolefin copolymers (COC)  
Polymethyyl methacrylate (PMMA)  
a derivative of one of these materials.

Claim 17. (currently amended)      A prism, comprising:  
a concave-shaped substrate consisting essentially of a plastic material which is temperature-stable up to at least 100° C.; and  
a reflecting surface on said substrate constructed as a cold-light mirror consisting essentially of a plurality of layers of different refraction coefficients applied to said substrate by means of one of: a plasma impulse (Pi) process, a chemical vaporization process (CVD) and a ~~phase~~plasma-impulse chemical vaporization process (PICVD).

Claim 18. (previously presented) The prism of claim 17 wherein said plurality of layers is applied by means of a chemical plasma-impulse vaporization process (PICVD).

Claim 19.( previously presented) The prism of claim 18 wherein the total duration of the plasma action amounts to at least 1/1000 of the total action-free time span, and is at most equal to this time span.

Claim 20. (previously presented) The prism of claim 19 wherein the coating rate of the plasma action lasts between 0.1 and 10 ms.

Claim 21. (previously presented) The prism of claim 19 wherein the coating rate of the plasma action per time unit and per surface unit is > 10 nanometers/min.

Claim 22. (previously presented) The prism of claim 17 wherein said substrate is a material selected from the group consisting of:

Cycloolefin polyers (COP)

Cycloolefin copolymers (COC)

Polymethyyl methacrylate (PMMA)

a derivative of one of these materials.

Respectfully submitted,

John F. Hoffman  
Registration No. 26,280

Attorney for Applicant

JFH/pmp

BAKER & DANIELS  
111 East Wayne Street, Suite 800  
Fort Wayne, IN 46802  
Telephone: 260-424-8000  
Facsimile: 260-460-1700

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